



VUE 400-P SCANNING ACOUSTIC MICROSCOPE

Semiconductor Package Failure Analysis
voids · disbonds · cracks · delamination · internal defects

Customer Interface

Dual 22" HD LED Monitors

Fixtures

Tray Fixture

Instrumentation

Digital Pulser Receiver Ultrasonic Digitizer (Max 12 GHz)

User Experience Elements

Dual JEDEC Trays HD LED Lighting ESD or Stainless Steel Tank

Maintenance Free Scan Axis

Motor: Quad Linear Servo
Max Velocity: 1500 mm/s
Accuracy & Repeatability: +/- 0.5 micron

Scan Envelope: 380 mm

Low Maintenance Step Axis:

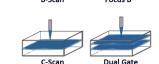
Step Envelope 350 mm

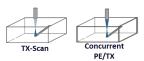
Low Maintenance Focus Axis:

Focus Envelope 50 mm

Dimensions:

0.9 m x 0.86 m x 1.18 m (W/D/H) 227 kg











VUE 400-P SCANNING ACOUSTIC MICROSCOPE

Included Software Modes:

- Basic (user friendly)
- Advanced (detailed analysis)
- Production (automated scanning)
- Off-line Analysis (virtual scanning)





OKOS Digital Imaging System (ODIS)



VUE 400-P imaging power surpasses modern standards delivering premium FA Lab features to semiconductor fabrication facilities. ODIS is the latest Acoustic Microscopy software with rich technical content built on current platforms and industry feedback. It includes both time domain and frequency domain imaging in real-time. Advanced analysis is provided through quantitative tools for measurement and classification of parts.

The Analysis version of ODIS allows non-scanning computers to virtually scan, view, and analyze data for simultaneous real-time analysis or post collection review. Supplied with your choice of Windows 7 or 10.

- · Counterfeit Detection · Product Inspection
- · Product Reliability
- · Quality Control
- · Process Validation
- · Failure Analysis
- · Vendor Oualification · R&D

Application Specific Transducers

for the highest quality resolution.

Multiple transducer design for enhanced scan capability.













